

MASS FLOW CONTROLLER GF-100-120-125

GF-100
Thermal Mass Flow Controller GF-100

- For all gases up to 10bar
- Metal sealed
- Service port aids device installation, monitoring and troubleshooting



PRODUCT DESCRIPTION

Brooks GF-100 series offer high purity flow path, outstanding performance, reliability, and repeatability.

Fast responding, repeatable delivery of process gases with high and ultra-high levels of purity—that's the performance the GF100 series of metal sealed mass flow controllers and meters provides. Designed for semiconductor, MOCVD and other gas flow control applications, the GF100 series exceeds the semiconductor industry standard for reliability, ensuring repeatable, highly stable performance over time. Standard MultiFlo™ technology enables one MFC to support thousands of gas types and range combinations without removing it from the gas line or compromising on accuracy.

Features:

- Long-term zero stability of $\leq \pm 0.5\%$ full scale per year
- Settling times: 700 ms - <1 second
- Full-scale flow rates up to 300 slpm
- All-metal seal flow path: option for 4 μ or 10 μ inch Ra surface finish
- Corrosion-resistant Hastelloy® T-Rise sensor improves measurement reproducibility at elevated temperatures
- MultiFlo™ gas and range programmability—one device, thousands of gas types and range combinations without removing the MFC from the gas line or compromising accuracy
- Local display
- Optional SDS gas delivery
- DeviceNet™, RS-485 L-Protocol and analog interfaces

SPECIFICATIONS

Approvals	CE, RoHS, SEMI F20 kompatibel, EN61010-1, EN61326: 2006 (FCC Part 15 & Canada IC-subset of CE testing)
Burst Pressure	206 bar
Control range	2-100 % (NC) 3-100 % (NO)
Data	RS485, DeviceNet
Diagnostics / Service Port	RS-485 via 2.5mm jack

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